



SHEET 1 OF 1

Substitute for forms 1449A/PTO & 1449B/PTO	ATTORNEY'S DKT No.	APPLICATION No.
	007413-056	10/614,825
	APPLICANT	
	Oliver KIENZLE et al.	
FIRST INFORMATION DISCLOSURE STATEMENT BY APPLICANT	FILING DATE	GROUP
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/s/	Hansheng GUO et al., "Charging Phenomena and Charge Compensation in AES on Metal Oxides and Silica," SURFACE AND INTERFACE ANALYSIS, Vol. 25, pp. 390-396 (1997), John Wiley & Sons, Ltd.
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Examiner Signature	Zia R. Hashmi	Date Considered	12/27/04
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